

Electronic Acknowledgement Receipt

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Title of Invention:	Method and apparatus for ionized plasma deposition
First Named Inventor:	Wei Wang
Customer Number:	44257
Filer:	Keith M. Tackett/Tammi Thomas
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Document Number	Document Description	File Name	File Size(Bytes)	Multi Part	Pages
1		003177D1Y1_RCE_EF.pdf	161474	yes	2

	Multipart Description		
	Doc Desc	Start	End
	Request for Continued Examination (RCE)	1	1
	Extension of Time	2	2
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